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LAM Research
4528i Oxide Etch 200mm Configuration
SN 3436

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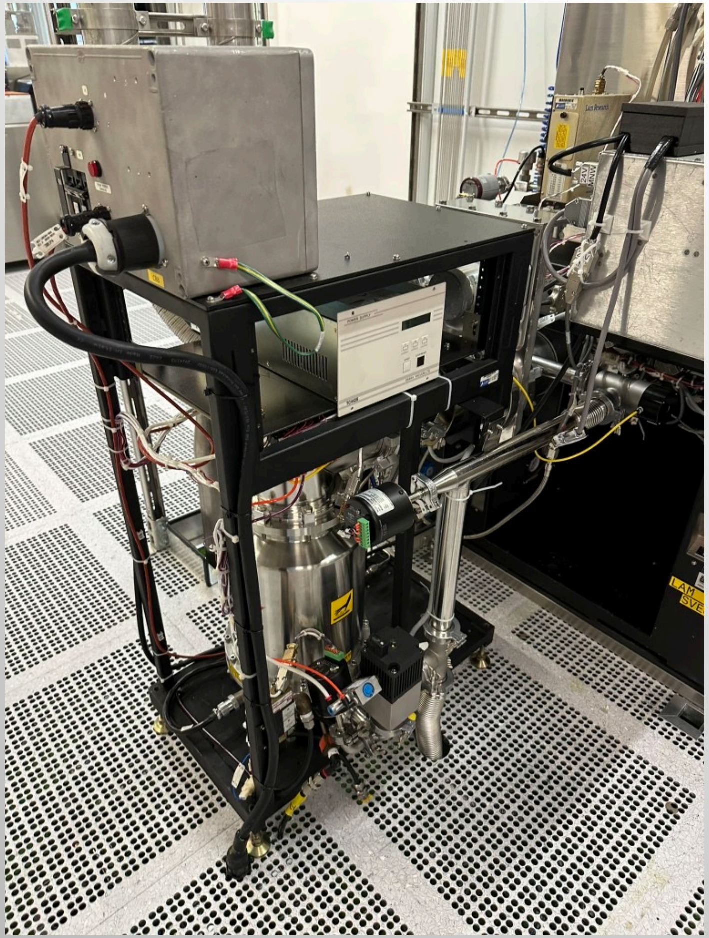

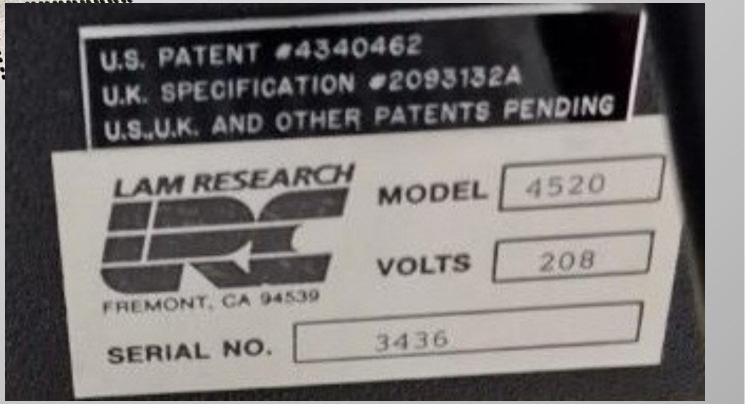
U.S. PATENT #4340462
U.K. SPECIFICATION #2093132A
U.S., U.K. AND OTHER PATENTS PENDING

LAM RESEARCH
FREMONT, CA 94539

MODEL 4520
VOLTS 208
SERIAL NO. 3436

LAM Research
4528i Oxide Etch SN 3436

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Tool Model : 4528i
Tool Serial Number : 3436
Bulkhead system mount w/tunnel covers
Hine 38A open cassette Send/Receive indexers
Software Version: Envision 1.6.1-005
Oxide etcher, 8”
Clamp type, ESC
RF power Rack ENI Paramount Plus VHF3027 / MF5002
Chiller Unit (LAM 2080)
AC Rack AC Power Distribution
Moving gap
Back Helium Colling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Aluminum upper chamber electrode

Single lower chamber endpoint detector (405/520nm)
Non--heated endpoint window
VAT 65 valve for chamber isolation
AC--2 chamber pressure control
8 -- Gas box Orbital gas box
Gas 1: AR 500 sccm
Gas 2: CF4 100 sccm
Gas 3: CHF3 100 sccm
Gas 4: C4F8 20 sccm
Gas 5:
Gas 6: O2 Low 20 sccm
Gas 7 O2 High 1000 sccm
Gas 8: N2 100 sccm
UPC: He (50 sccm)
AC input box for AC power inlet
Trip breakers AC/DC power box

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